

1           ABSTRACT OF THE DISCLOSURE

2           A semiconductor processing workpiece support which includes a  
3           detection subsystem that detects whether a wafer or other workpiece is  
4           present. The preferred arrangement uses an optical beam emitter and  
5           an optical beam detector mounted along the back side of a rotor which  
6           acts as a workpiece holder. The emitted beam passes through the  
7           workpiece holder and is reflected by any workpiece present in the  
8           workpiece holder. The preferred units include both an optical emitter  
9           and pair of detectors. The detection is preferably able to discriminate  
10          on the basis of the angle of the reflected beam, so that a portion of  
11          the beam reflected by the workpiece holder is not considered or  
12          minimized.

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